

PATENT
Docket No. 150.00810102IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Brian A. Vaarstra

Group Art Unit: 2823

Serial No.: 09/865,612

Examiner: G. Fourson III

Confirmation No.: 4967

Filed: May 25, 2001

For:

METHODS, COMPLEXES, AND SYSTEMS FOR FORMING METAL-
CONTAINING FILMS ON SEMICONDUCTOR STRUCTURES

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Attn: Examiner G. Fourson III
Washington, D.C. 20231FAX NUMBER: (703)308-7722
Total Pages (including cover page): 20
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PATENT
Docket No. 150.00810102#8/Response
6/5/03
MIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Brian A. Vaartstra) Group Art Unit: 2823
Serial No.: 09/865,612) Examiner: G. Fourson III
Confirmation No.: 4697)
Filed: May 25, 2001)
For: METHODS, COMPLEXES, AND SYSTEMS FOR FORMING METAL-CONTAINING FILMS ON SEMICONDUCTOR STRUCTURES

RESPONSE

Assistant Commissioner for Patents
Washington D.C. 20231

Dear Sir:

In response to the Office Action mailed December 3, 2002, please consider the following remarks:

Remarks

The Office Action mailed December 3, 2002 has been received and reviewed. Reconsideration and withdrawal of the rejections are respectfully requested.

Rejection under 35 U.S.C. §102

The Examiner rejected claims 18-38 under 35 U.S.C. §102(a) as being anticipated by the Examiner's Taking of Official Notice. Specifically, the Examiner has taken Official Notice that "CVD systems including those adapted as recited in claim 20 for example were known prior to applicant's invention." Applicant respectfully traverses the rejection.

"[F]or anticipation under 35 U.S.C. 102, the reference must teach *every aspect* of the claimed invention either explicitly or impliedly." M.P.E.P. §706.02 (emphasis added). Independent claims 18, 19, 33, and 38 each recite, among other things, a chemical vapor deposition system including a vessel containing *a precursor including one or more complexes of the formula: $[(R^1)NC(R^2)C(R^3)N(R^4)]_xML_y$*